IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: GEUN-YOUNG YEOM, ET AL.

FOR: METHOD OF ETCHING SEMICONDUCTOR DEVICE USING NEUTRAL BEAM AND APPARATUS FOR ETCHING THE SAME

PRELIMINARY AMENDMENT

Commissioner of Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Prior to examining the indicated application, amend as set forth herein:

Amendments to the Claims begin on page 2 of this paper; and

Remarks begin on page 3 of this paper.